

FIG 1: PLASMA SPUTTER DEPOSITION SYSTEM

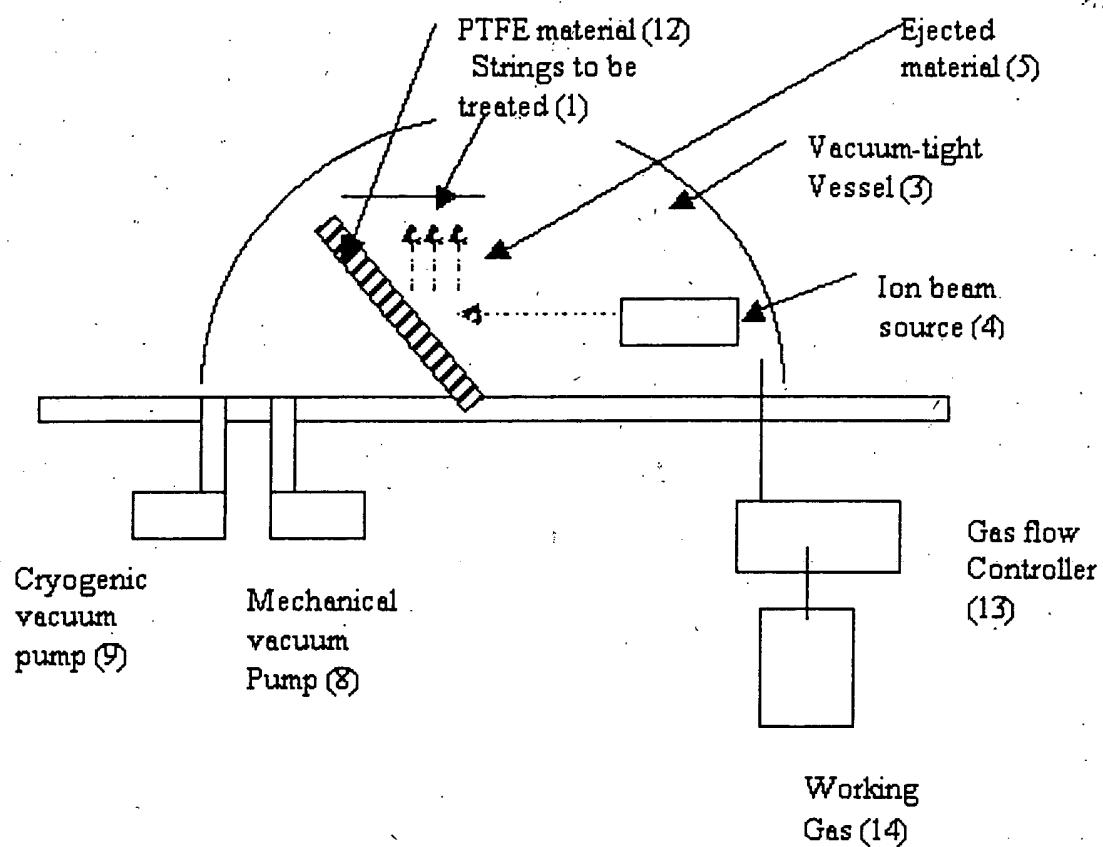


FIG 2: ION BEAM DEPOSITION SYSTEM

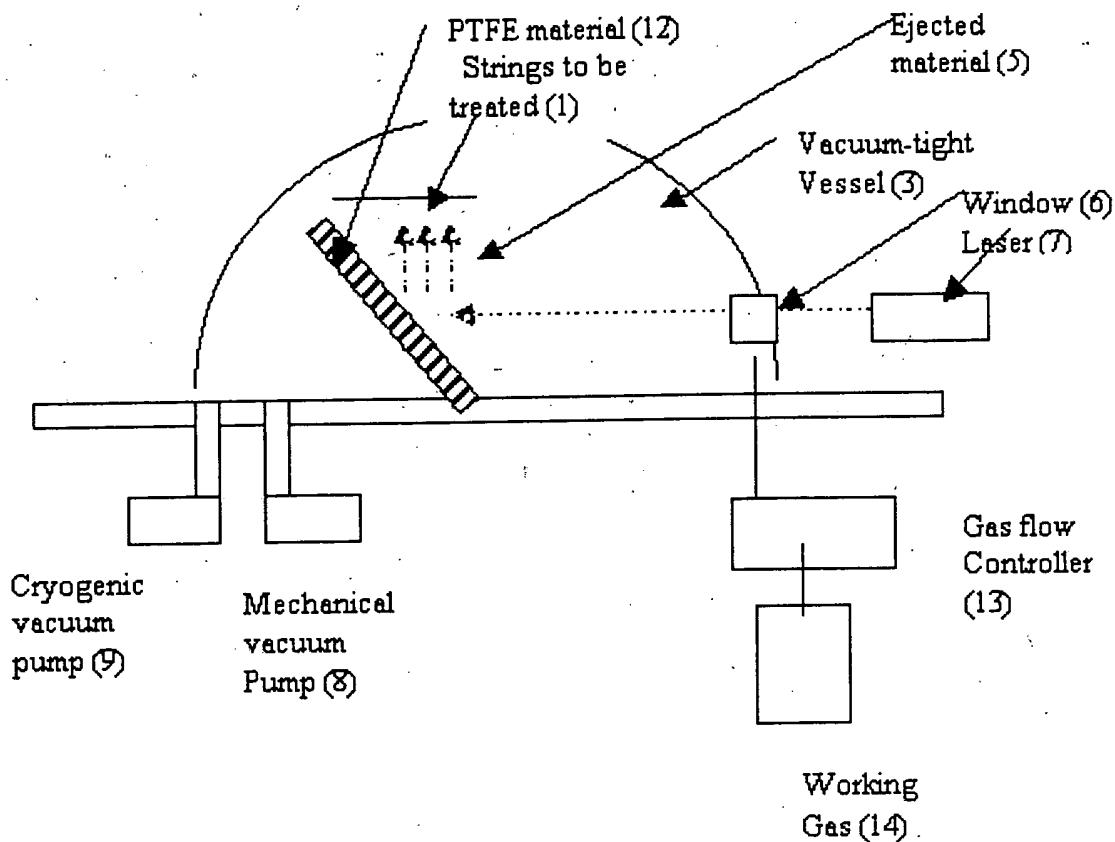


FIG 3: LASER DEPOSITION SYSTEM

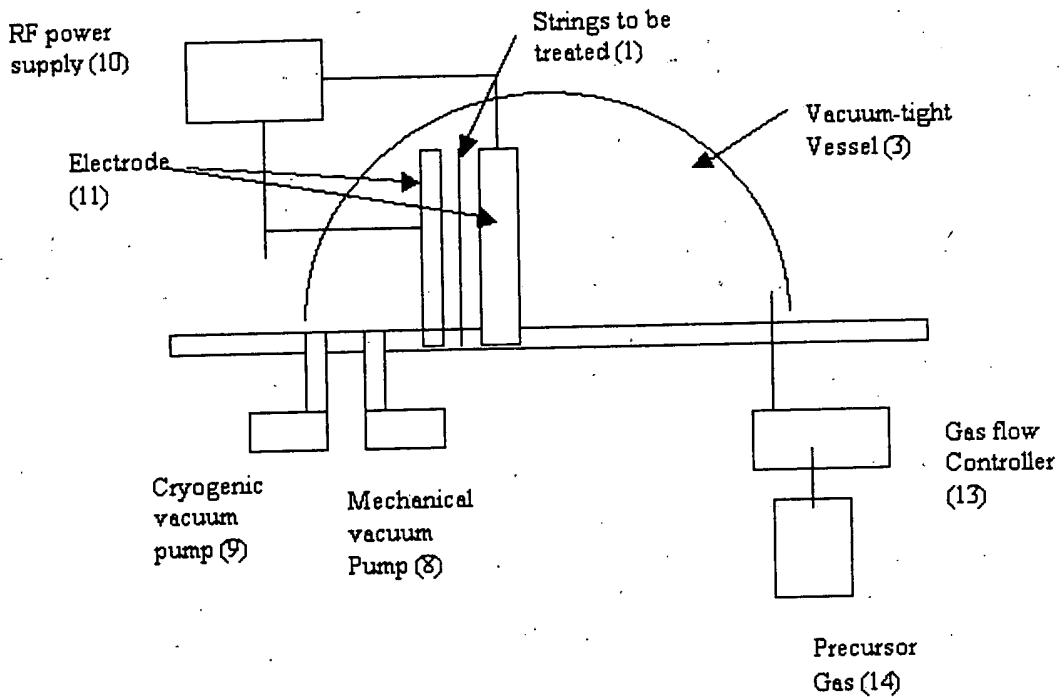


FIG 4: PLASMA CHEMICAL VAPOR DEPOSITION SYSTEM

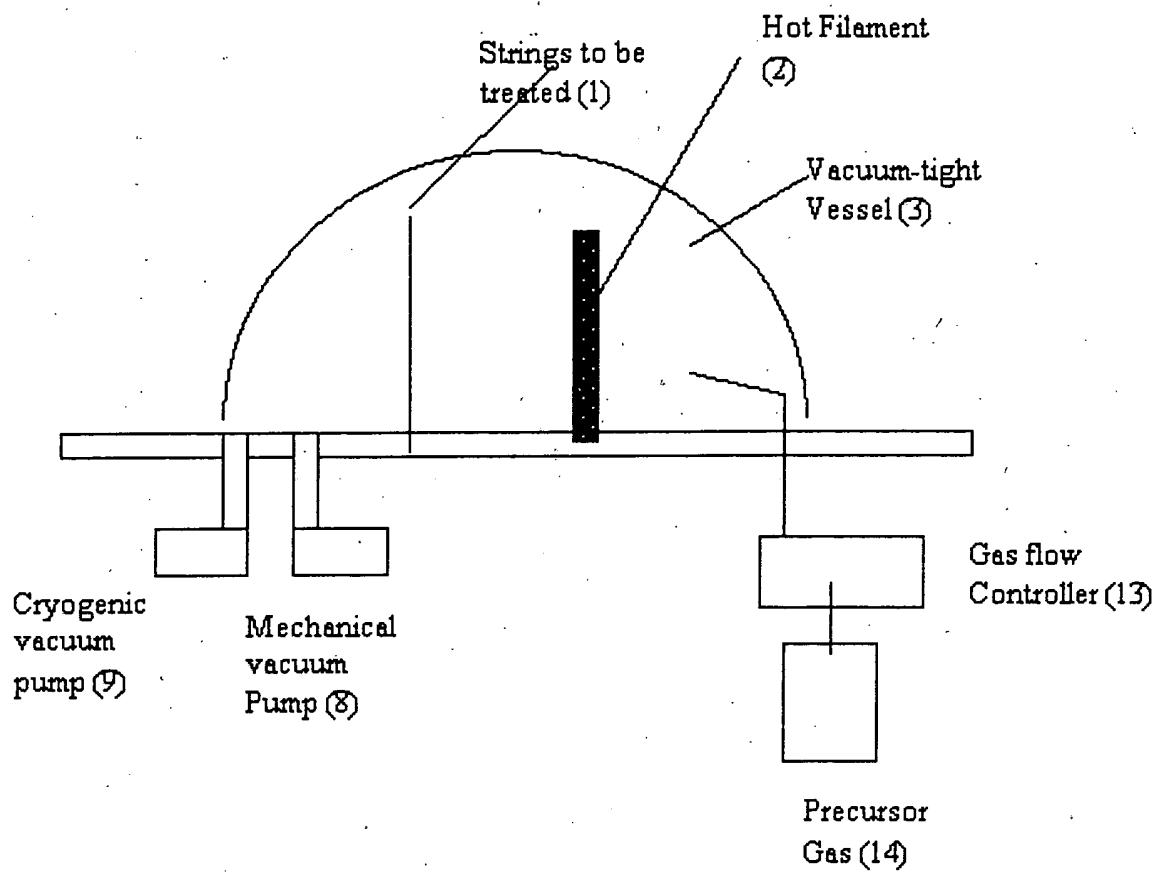


FIG 5: HOT FILAMENT CHEMICAL VAPOR DEPOSITION SYSTEM

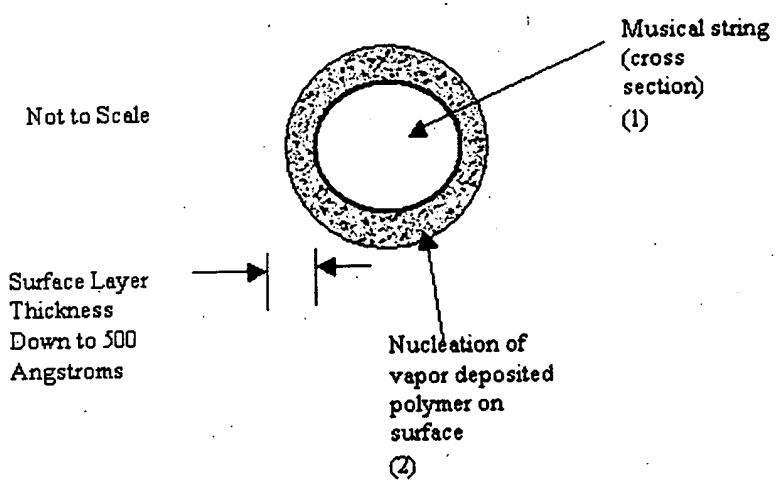
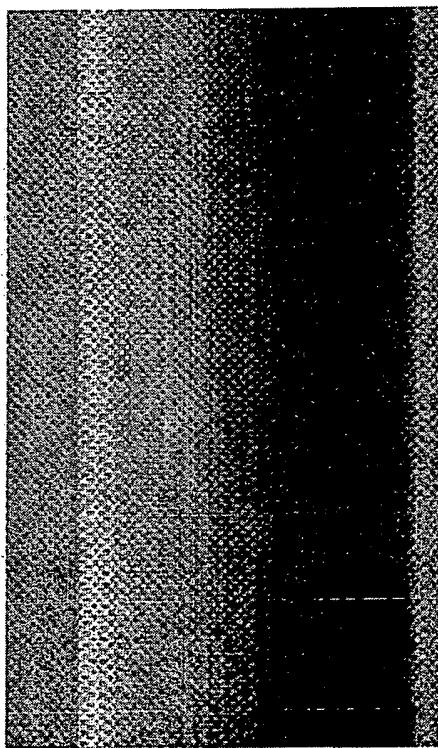


FIGURE 6: MUSICAL STRING TREATED WITH VAPOR DEPOSITED POLYMER

10002789 . 060602



*FIGURE 7*

300 1 40

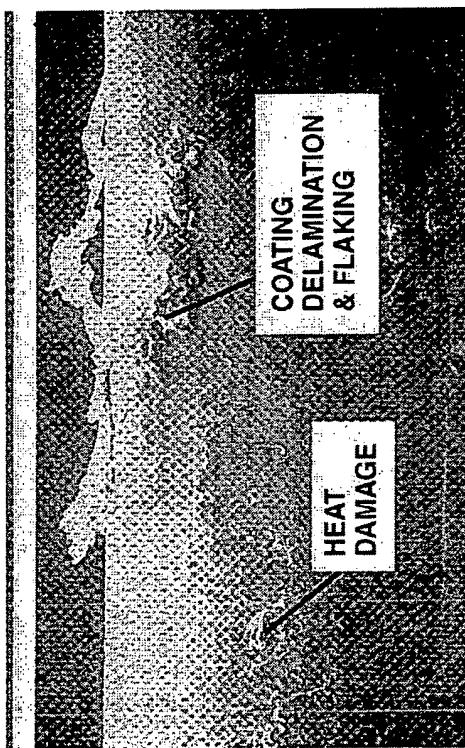


FIGURE 8

10002789 060602

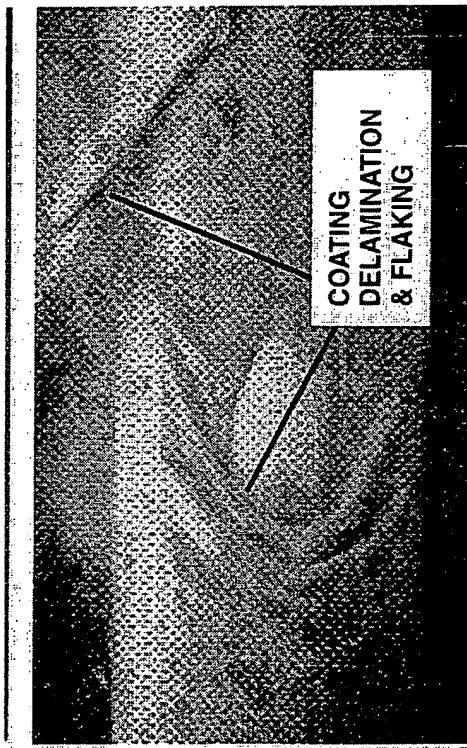
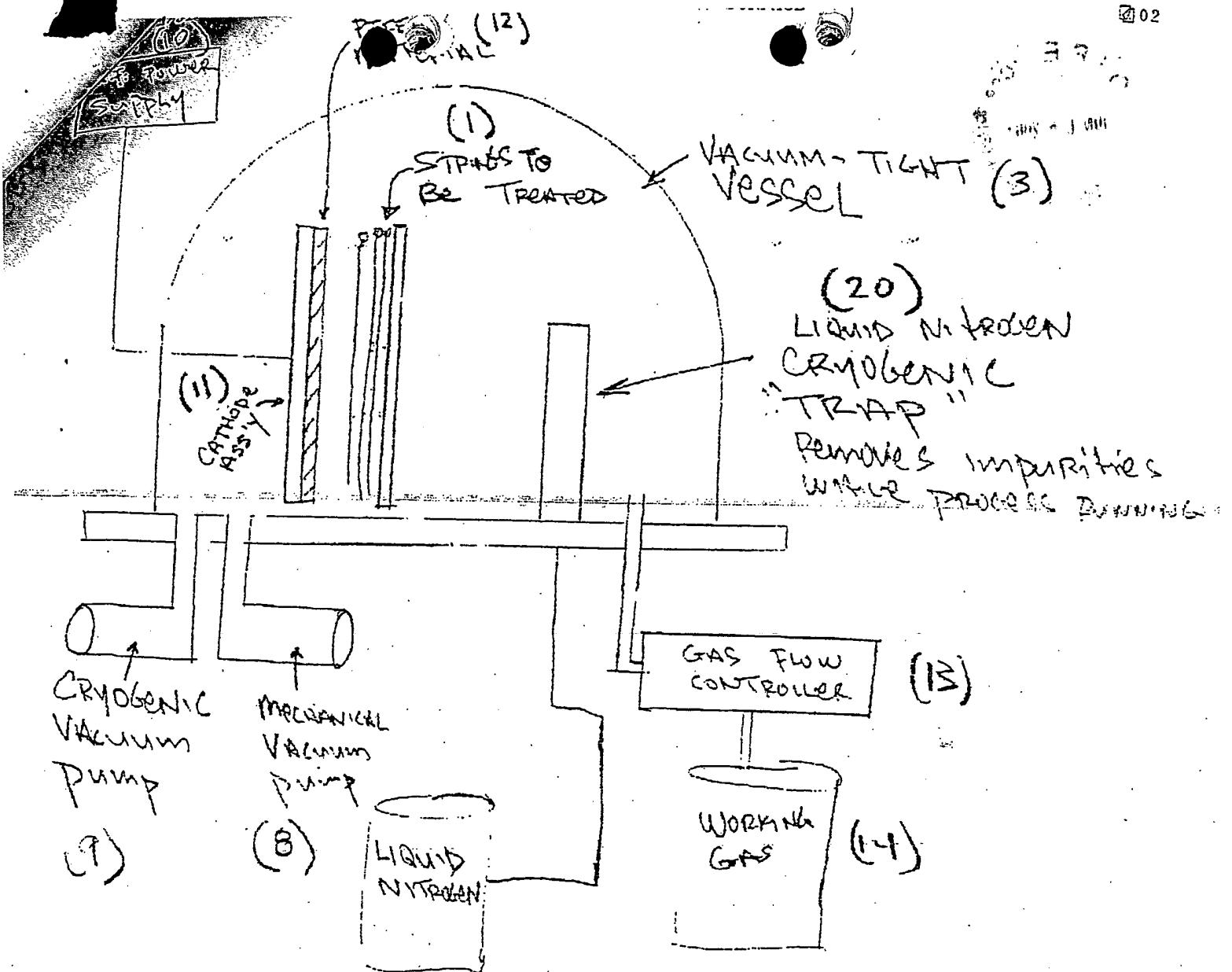
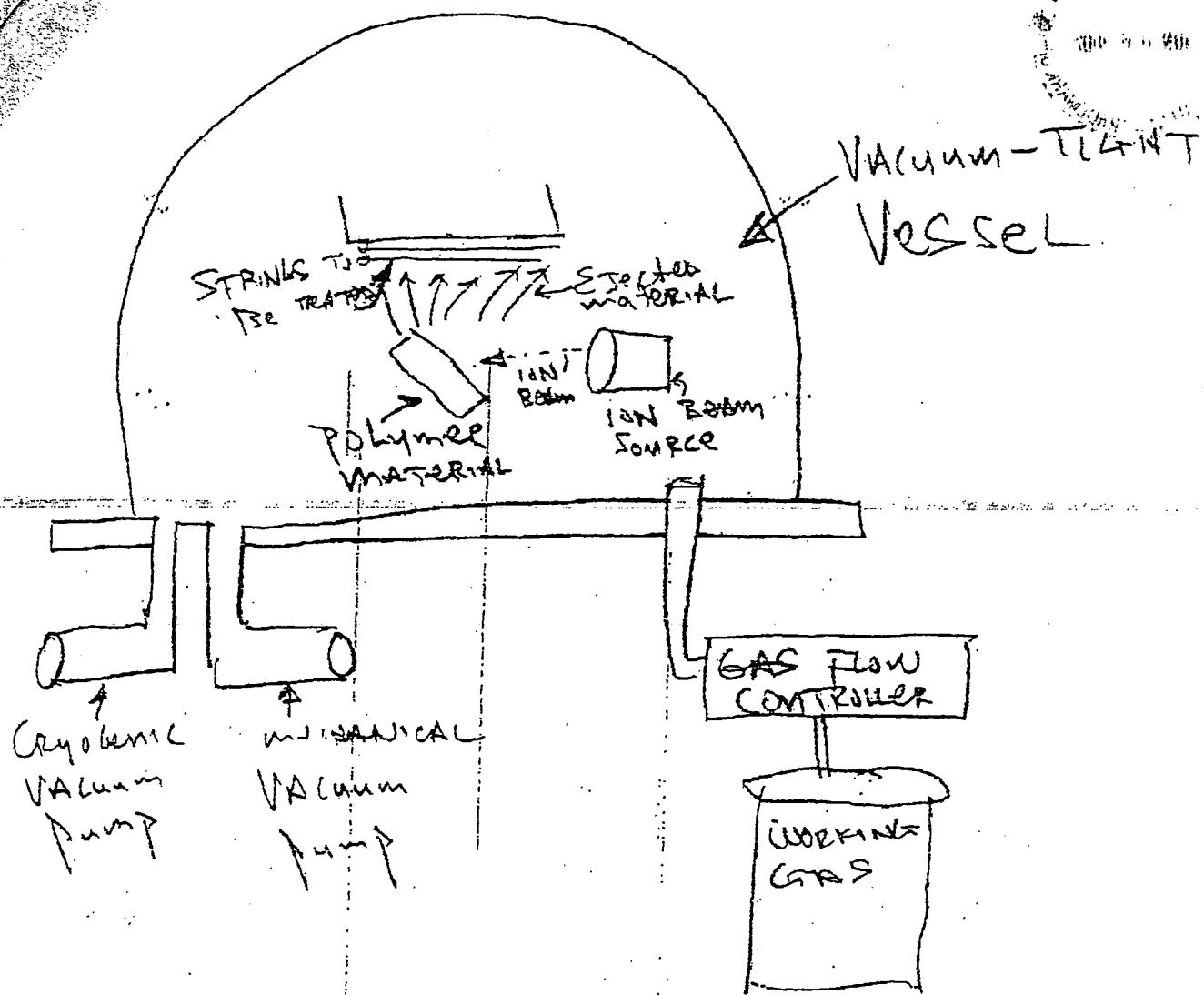


FIGURE 9



## PLASMA SPUTTER DEPOSITION

Fig. 1



ION Beam Sputtering

Fig. 2

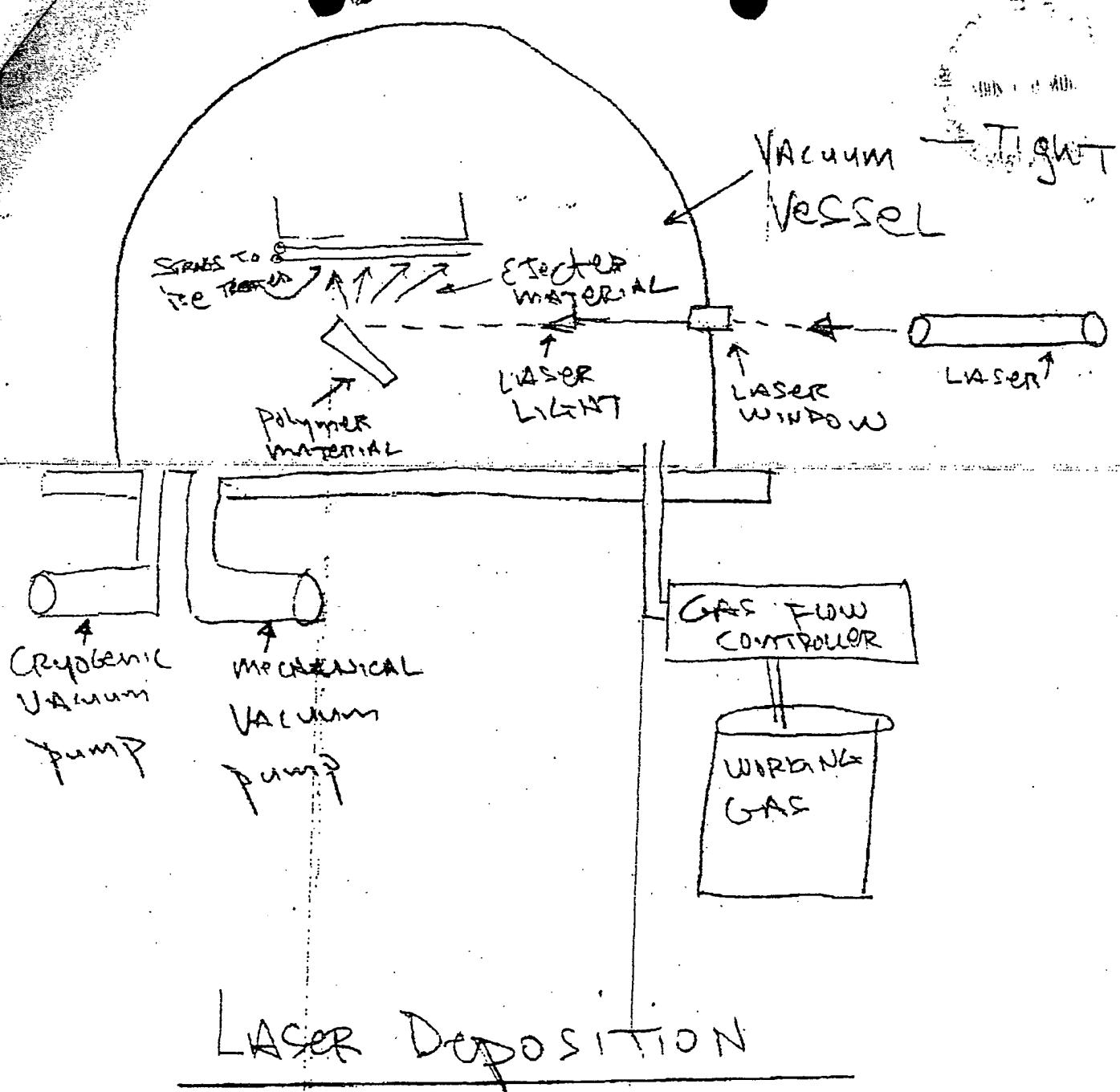
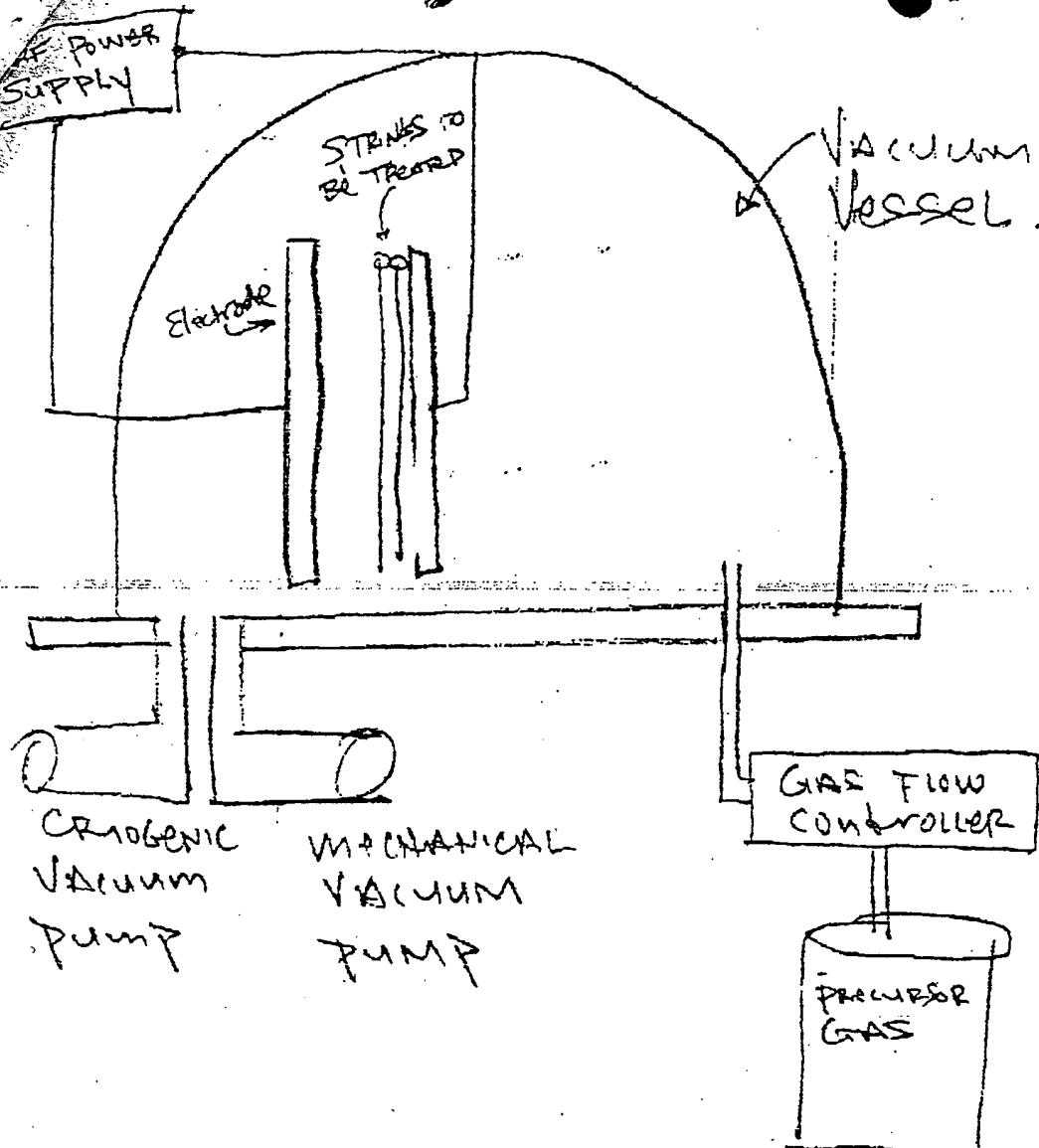
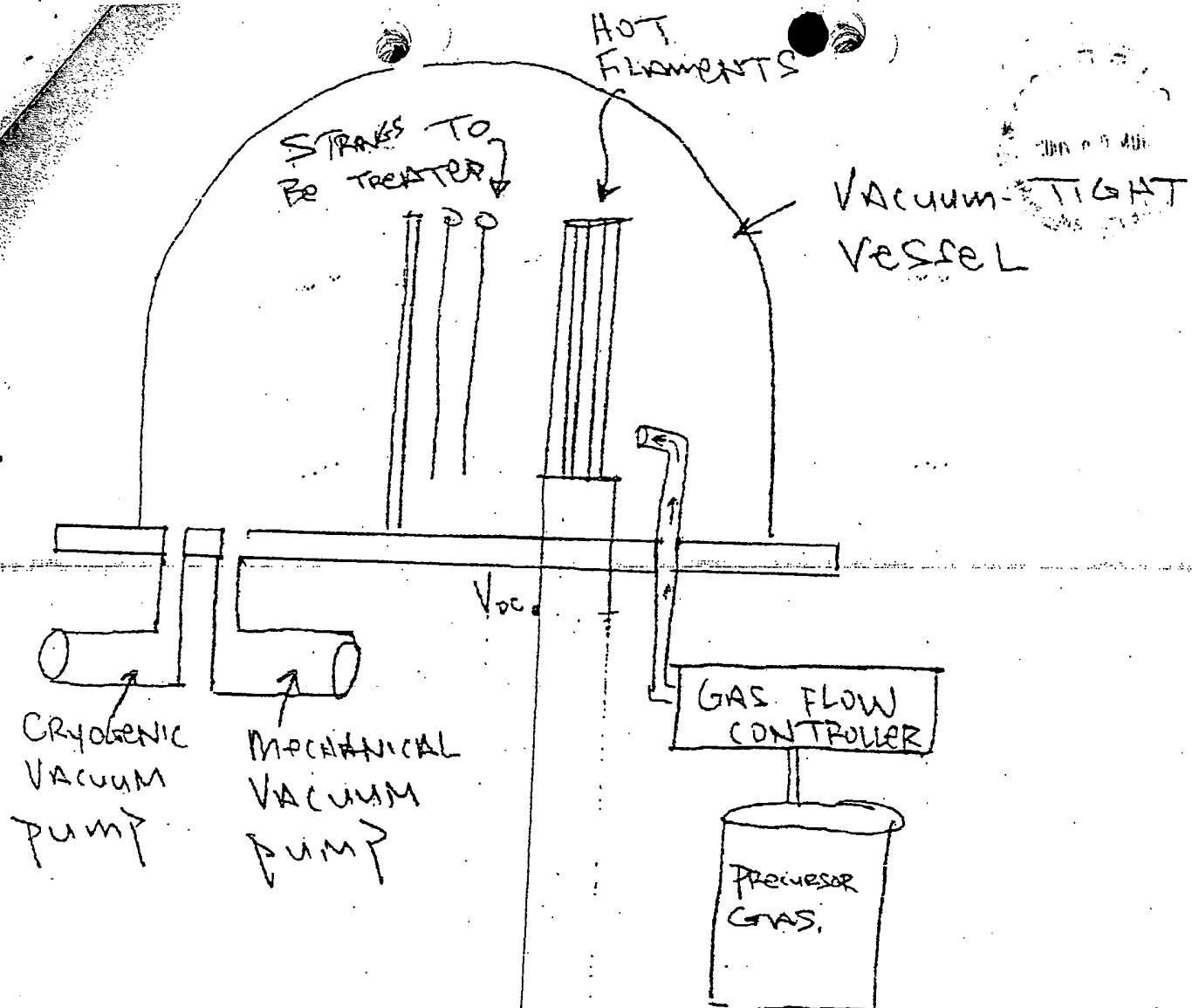


FIG 3



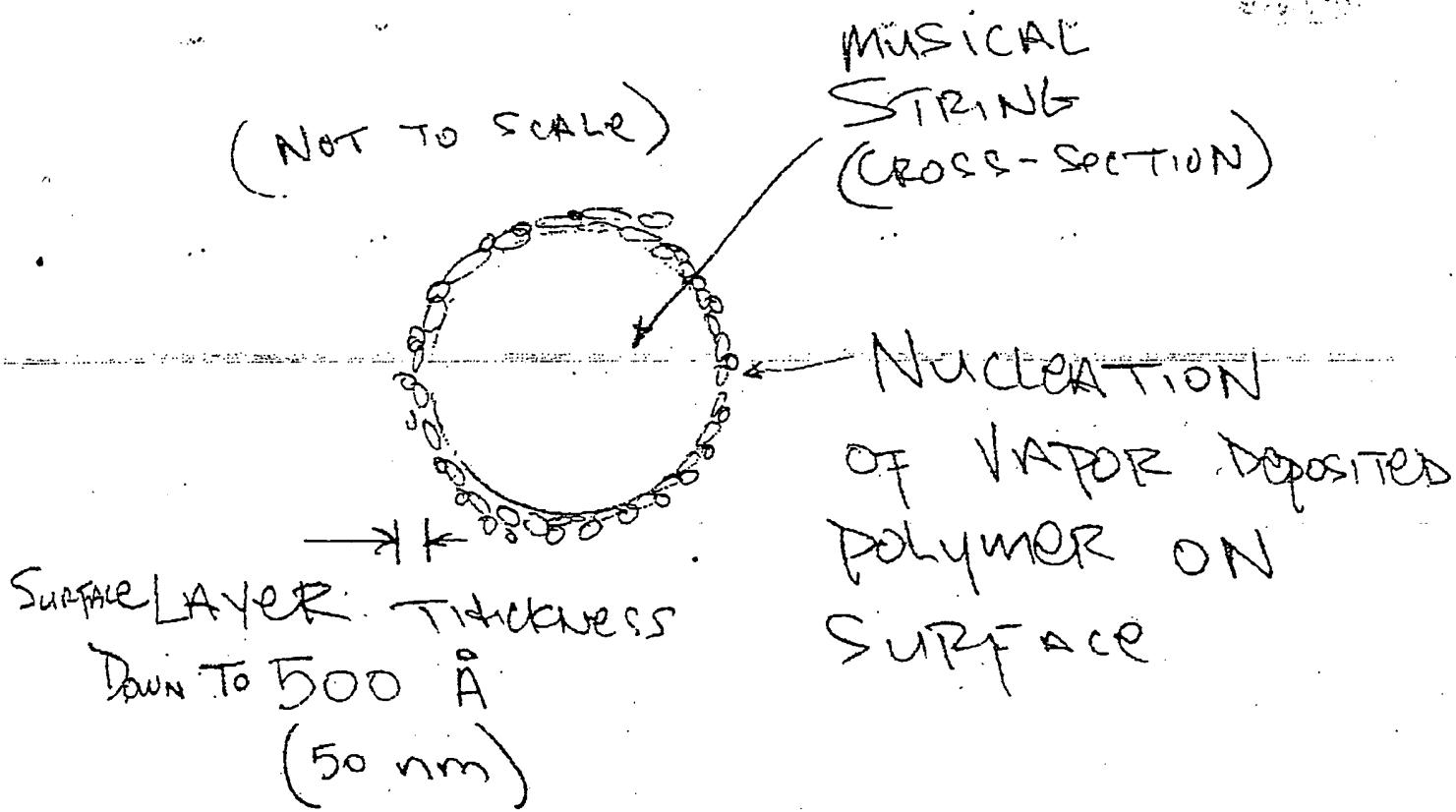
## PLASMA CHEMICAL VAPOR DEPOSITION

FIG. 4



HOT FILAMENT CHEMICAL VAPOR  
DEPOSITION

Fig 5



### MUSICAL INSTRUMENT STRING TREATED

W/ VAPOR DEPOSITED POLYMER NUCLEATE

FIG 6

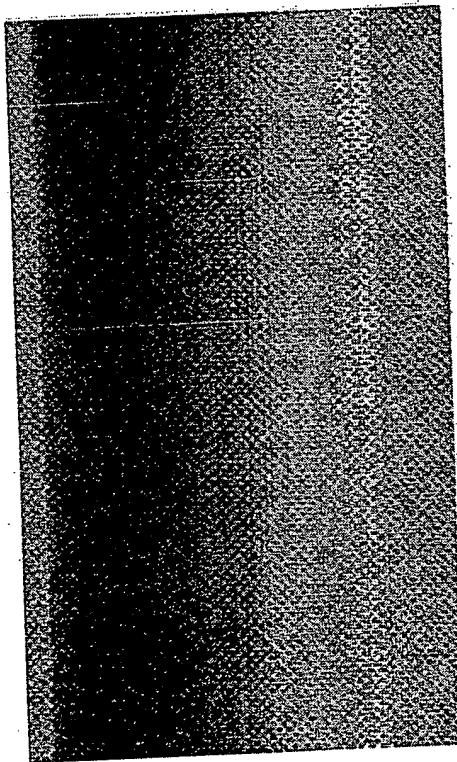
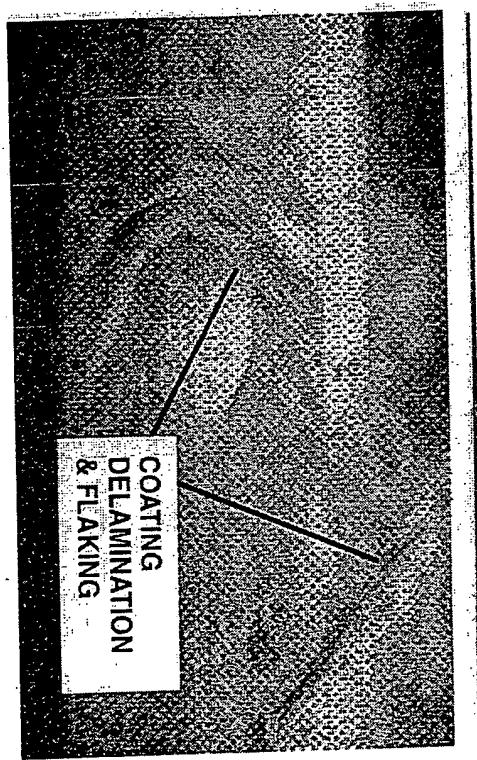


FIG 7

FIG 8



FIG 9



### Substitute drawings (9)

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